

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of

FUJII et al.

Appln. No.: Division of 09/181,615

This Division Filed: Herewith

For: SEMICONDUCTOR MECHANICAL SENSOR

3 / Prel. amdt.
B
E. Willis
3-5-01

Group Art Unit: 2856

Examiner: KWOK, H.

* * * * *

December 28, 2000

PRELIMINARY AMENDMENT

Hon. Commissioner of Patents
Washington, D.C. 20231

Sir:

Kindly preliminarily amend this divisional application as follows:

IN THE SPECIFICATION:

Page 1, line 7, after "a" insert a method of manufacturing a--;

line 8, delete "and Method of Manufacture";

line 9, delete "of manufacturing the"; and change "an" to a method

for manufacturing a--;

line 10, delete "and a method of";

delete line 11 in its entirety;

line 14, change "sensor or" to --sensor,--; before "sensors" insert --or--;

line 33, after "to" insert provide a method of manufacturing a sensor

to--.